



**AZ Electronic Materials**

# **AZ<sup>®</sup> 15nXT (450 CPS) Photoresist**

**Negative Acting Thick Resist for  
Cu RDL, TSV, and other plating & etch applications**

**Lithographic and Plating Performance Comparison  
at 10  $\mu\text{m}$  FT on Cu wafers**

**January 2009**

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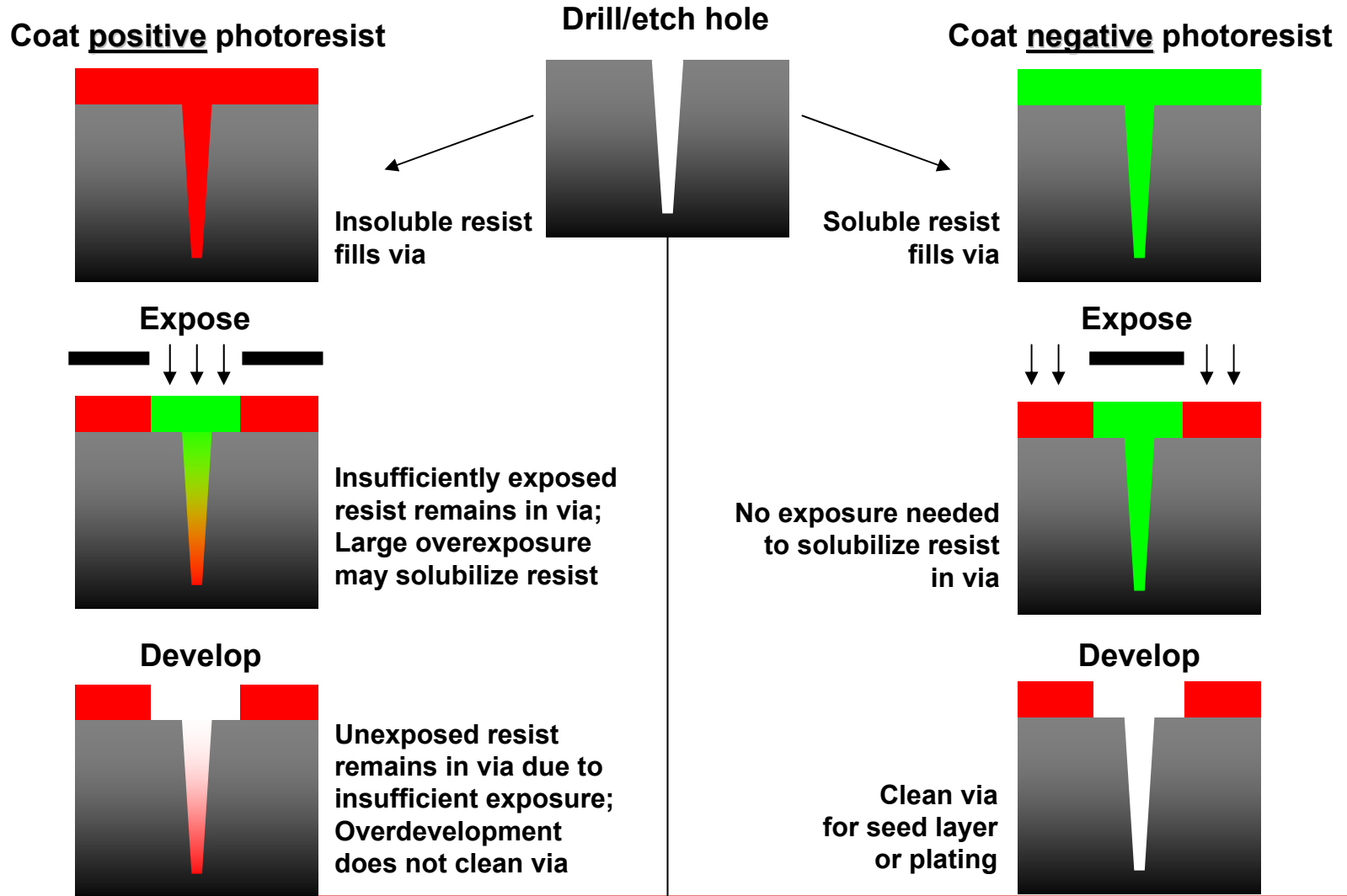
# AZ's Thick Film Photoresist Roadmap

Lift-off FT: 2-10 $\mu\text{m}$	TSV / Etch Implant, Plating FT: 3-15 $\mu\text{m}$	Copper/UBM Plating FT: 5-30 $\mu\text{m}$	Gold Plating FT: 10-30 $\mu\text{m}$	Solder / Metal Plating FT: >30 $\mu\text{m}$	MEMS / Ink Jet FT: >30 $\mu\text{m}$	DUV TFRH/Implant FT: 3 - 8 $\mu\text{m}$	
Commercialized materials		P4620					
AZ <sup>®</sup> nLOF Series	AZ <sup>®</sup> 10XT		AZ <sup>®</sup> 50XT		AZ <sup>®</sup> TX 1311		
	AZ <sup>®</sup> 9200		AZ <sup>®</sup> 40XT-11D		AZ <sup>®</sup> VS-01HJ		
	AZ <sup>®</sup> N4000	AZ <sup>®</sup> 4562	AZ <sup>®</sup> PLP30/PLP40				
Materials in sampling (all products)		AZ <sup>®</sup> 125nXT Series				AZ <sup>®</sup> TX VS-02HJ	
AZ <sup>®</sup> 12XT Series							
AZ <sup>®</sup> 15nXT							
Materials under development		AZ <sup>®</sup> EXP 100				AZ <sup>®</sup> LExp 600	

Red=Neg, Blue =Pos; nLOF, N4000, 5nXT/15nXT, 12XT, 40XT = chemically amplified; 125nXT = photopolymer; 10XT, 9200, P4620, PLP, 50XT, 4500 = DNQ

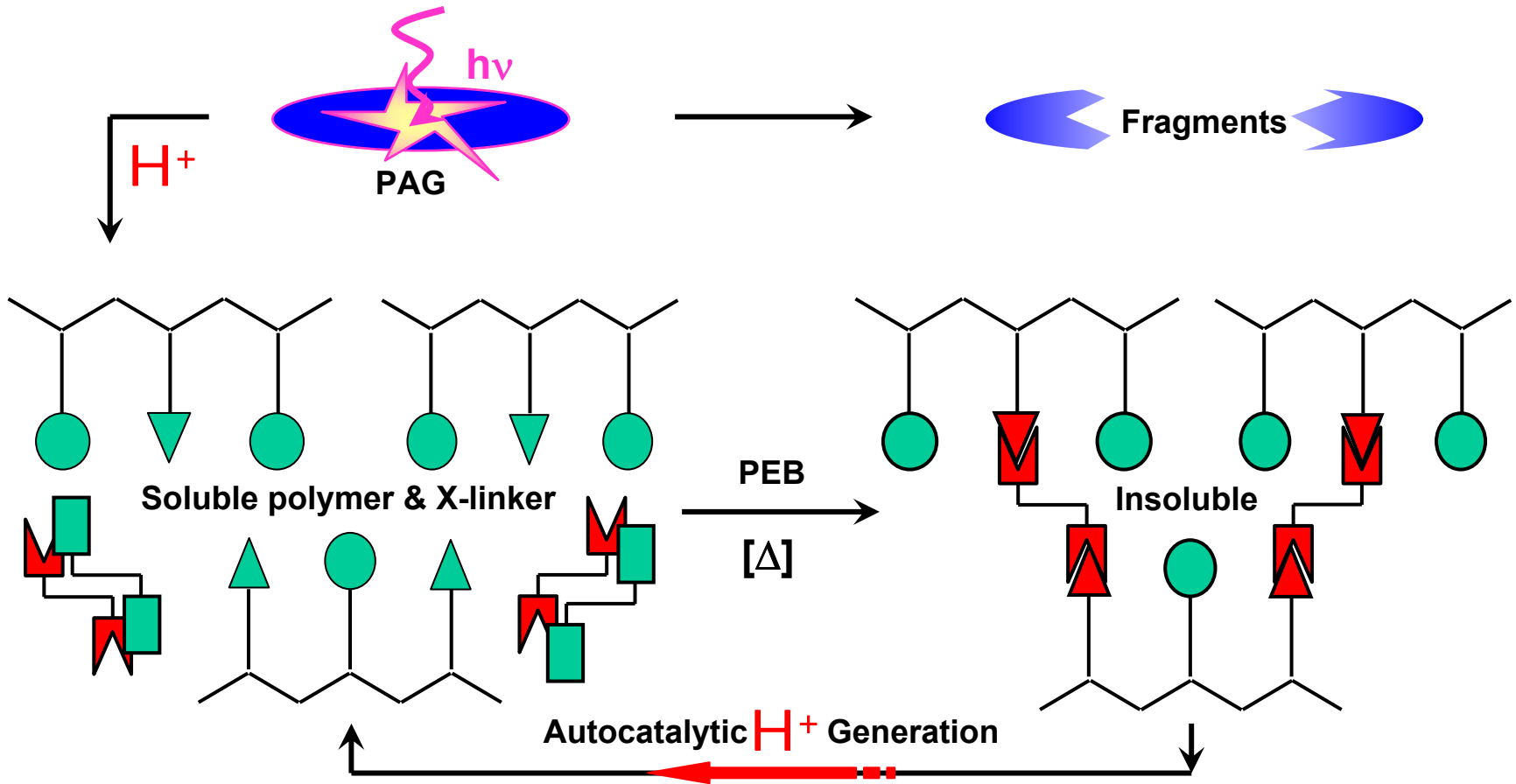
# Through-Silicon-Via (TSV)

## Advantages to Use a Negative Photoresist



# Chemically Amplified Negative Resist

The original photo-event generates a catalyst for crosslinking (typically a proton).  
The photo-event is amplified by the number of cycles each proton catalyzes.



# AZ<sup>®</sup> 15nXT (450 CPS)

## Process Conditions

Substrate:	Si wafer for photospeed testing Cu wafer for images
Film Thickness:	10µm by single coat
Softbake:	110°C / 180 seconds
Exposure tool:	ASML (i-line) Dose = $400 \pm 50$ mJ/cm <sup>2</sup> ; Focus: $1 \pm 0.5$ µm
PEB:	120°C / 60 seconds
Develop:	AZ 300 MIF (2.38% TMAH); 3 x 50 second puddles

# AZ<sup>®</sup> 15nXT (450 CPS)

## Optical Parameters

n & k Values at different wavelength

365 nm: n = 1.6807                      k = 0.0027

633 nm: n = 1.6063                      k = 0.0034

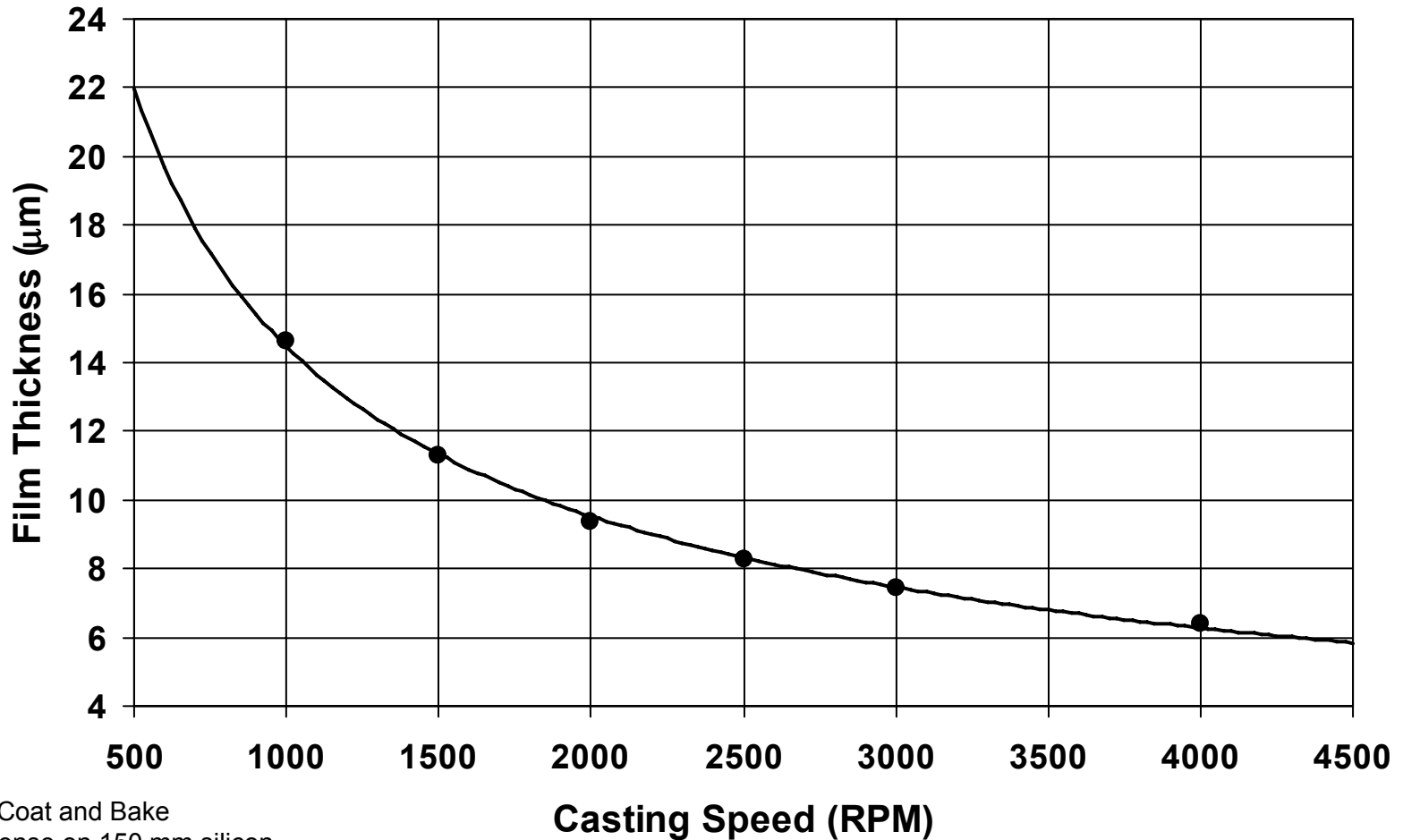
Cauchy coefficients (A, B, C) fit the following Cauchy equation:  $n = A + B/\lambda^2 + C/\lambda^4$

A = 1.5754

B = 0.013242  $\mu\text{m}^2$

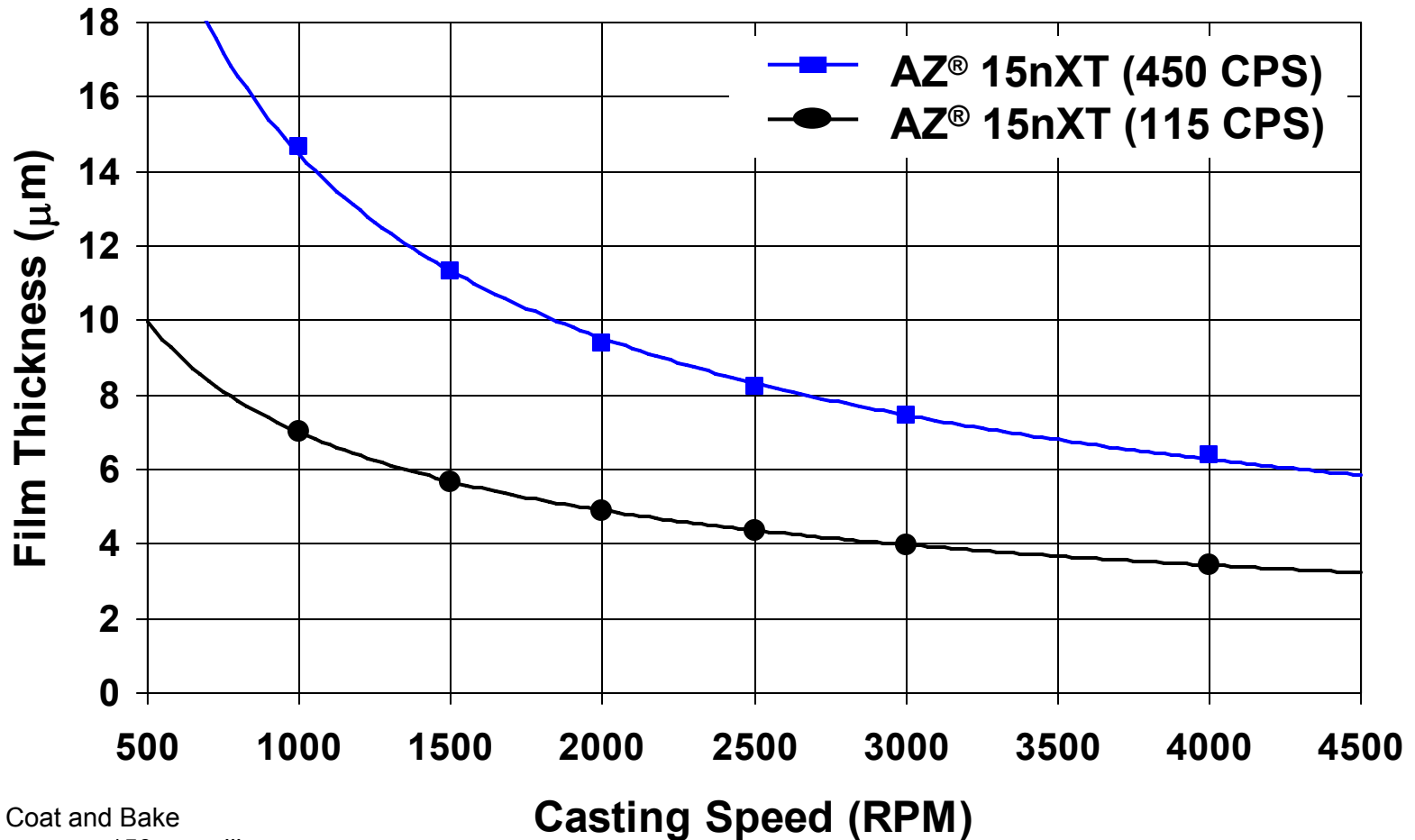
C = 0  $\mu\text{m}^4$

# AZ<sup>®</sup> 15nXT (450 CPS) Spin Speed Curve



Opti-Trak Coat and Bake  
Hand dispense on 150 mm silicon  
Spin 1000-4000 rpm for 30 sec  
SB: 110°C/ 3 minutes

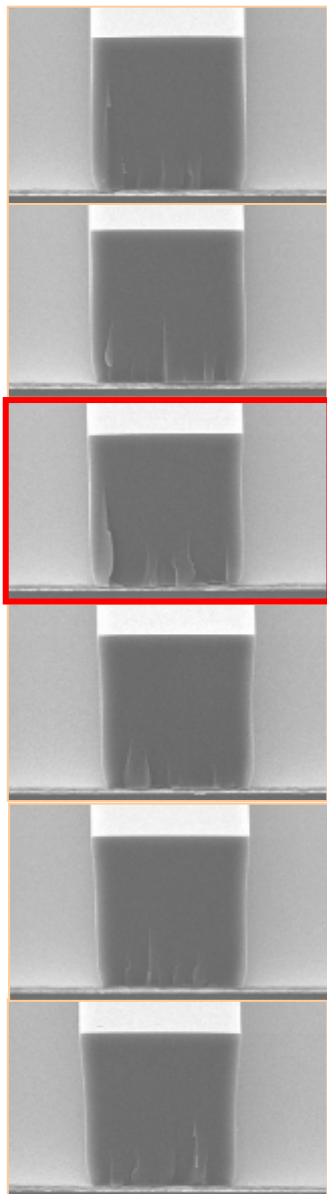
# AZ<sup>®</sup> 15nXT (115 CPS) and AZ<sup>®</sup> 15nXT (450 CPS) Spin Speed Curves



Opti-Trak Coat and Bake  
Hand dispense on 150 mm silicon  
Spin 1000-4000 rpm for 30 sec  
SB: 110°C/ 3 min for 15nXT  
110°C/2 min for 5nXT



10µm



# AZ<sup>®</sup> 15nXT (450 CPS)

## Depth of Focus

0.0 µm

0.5 µm

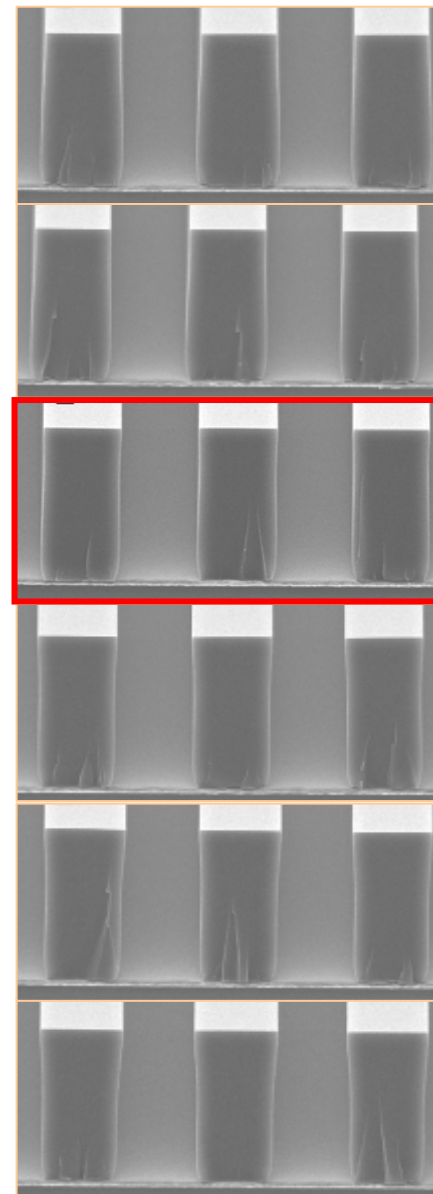
1.0 µm

1.5 µm

2.0 µm

2.5 µm

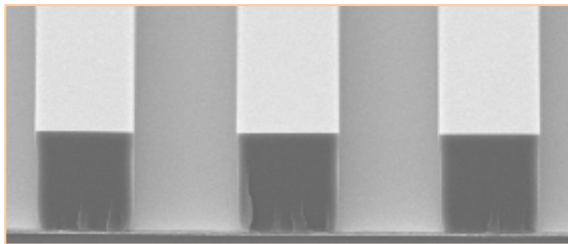
5µm



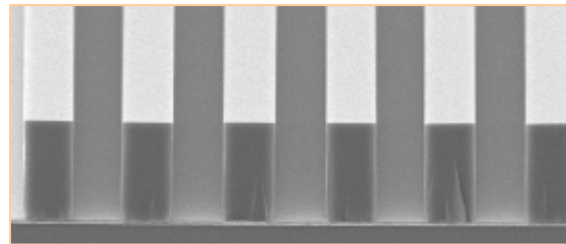
# AZ<sup>®</sup> 15nXT (450 CPS)

## Linearity, Resolution

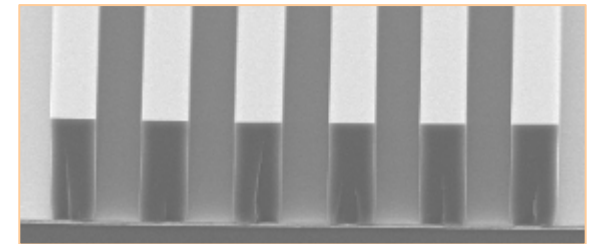
400 mJ/cm<sup>2</sup>, F = 1 μm



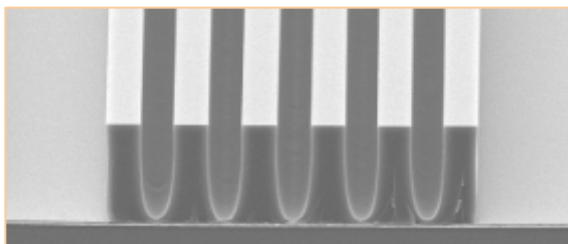
10 μm



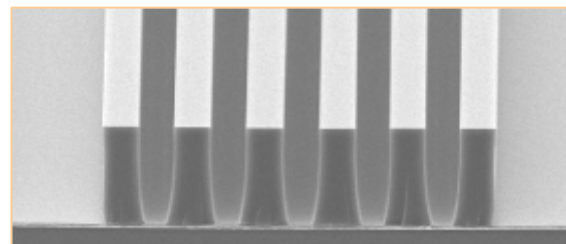
5 μm



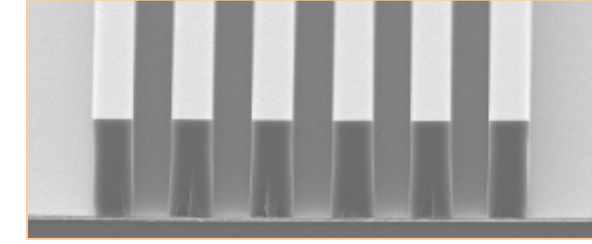
4.5 μm



3.4 μm



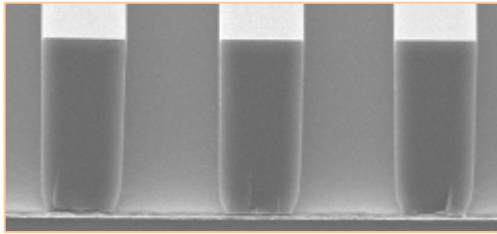
3.6 μm



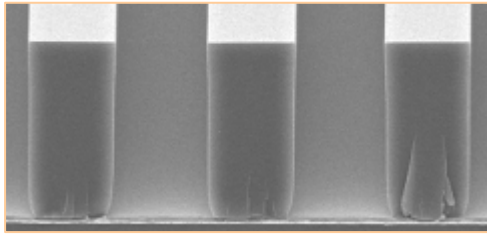
4 μm

# AZ<sup>®</sup> 15nXT (450 CPS) - Exposure Latitude

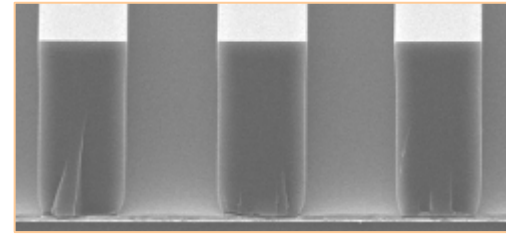
FT = 10 μm, Focus = 1.0 μm, 5.0 μm L/S on Cu Wafers



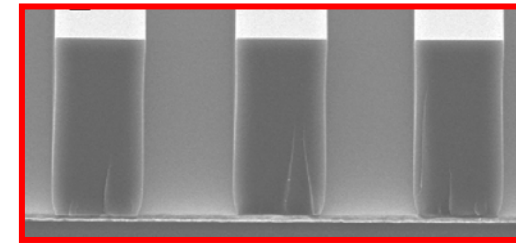
250 mJ/cm<sup>2</sup>



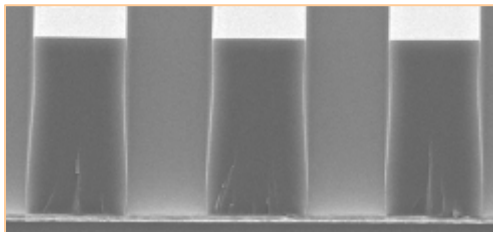
300 mJ/cm<sup>2</sup>



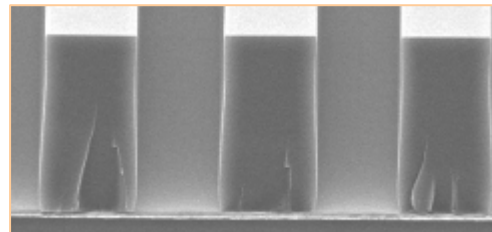
350 mJ/cm<sup>2</sup>



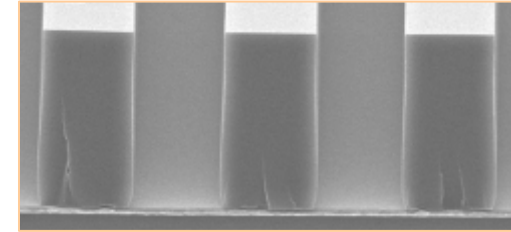
400 mJ/cm<sup>2</sup>



550 mJ/cm<sup>2</sup>



500 mJ/cm<sup>2</sup>

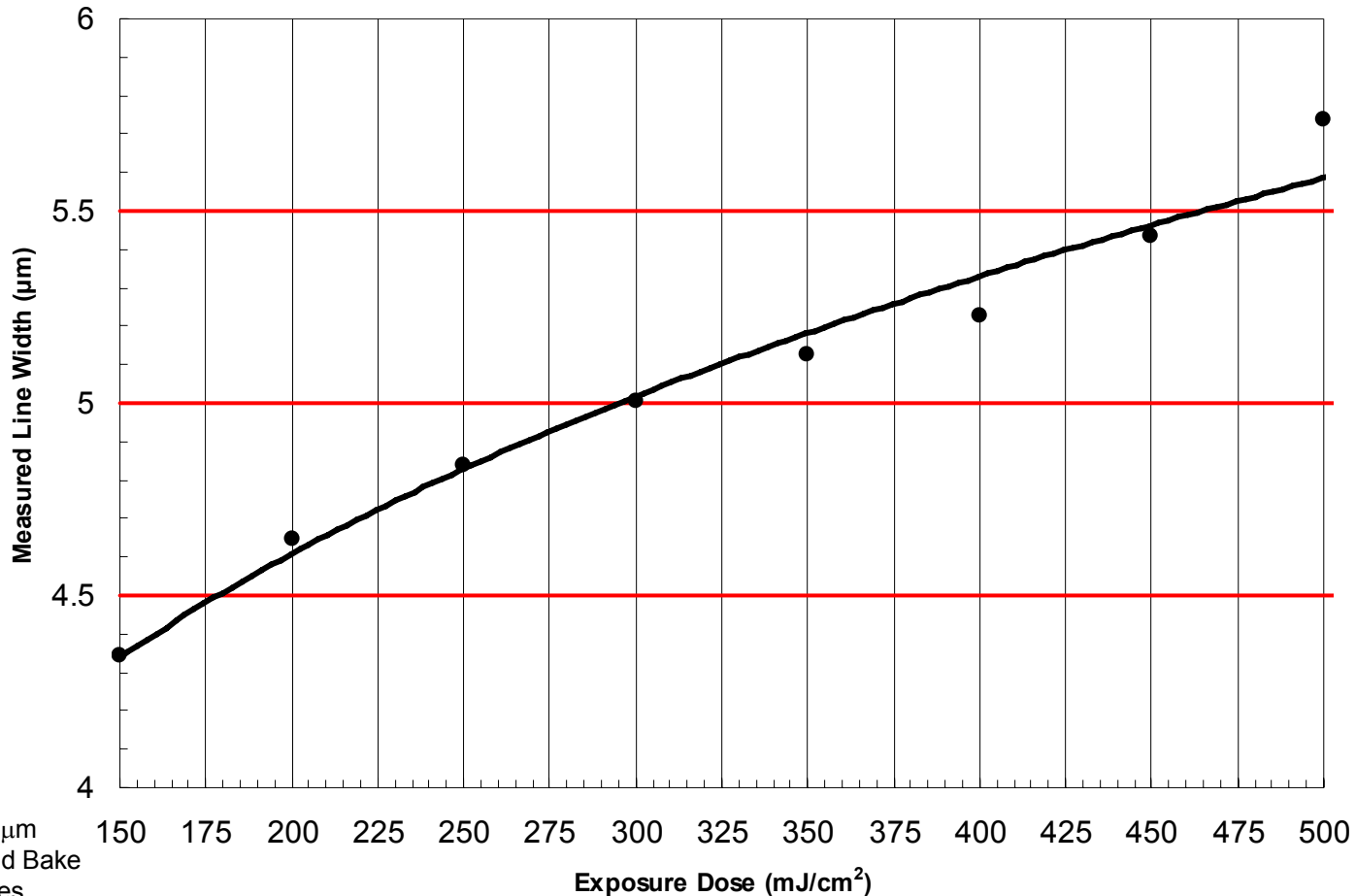


450 mJ/cm<sup>2</sup>

Film Thickness: 10μm  
Opti Track Coat and Bake  
SB: 110°C/3 minutes  
ASML i-Line Stepper, F= +1.0μm  
Opti Track PEB/Develop  
PEB: 120°C/ 60 Seconds  
AZ 300 MIF/ 3x50sec Spray/Puddle @23°C

# AZ<sup>®</sup> 15nXT (450 CPS) - Exposure Latitude

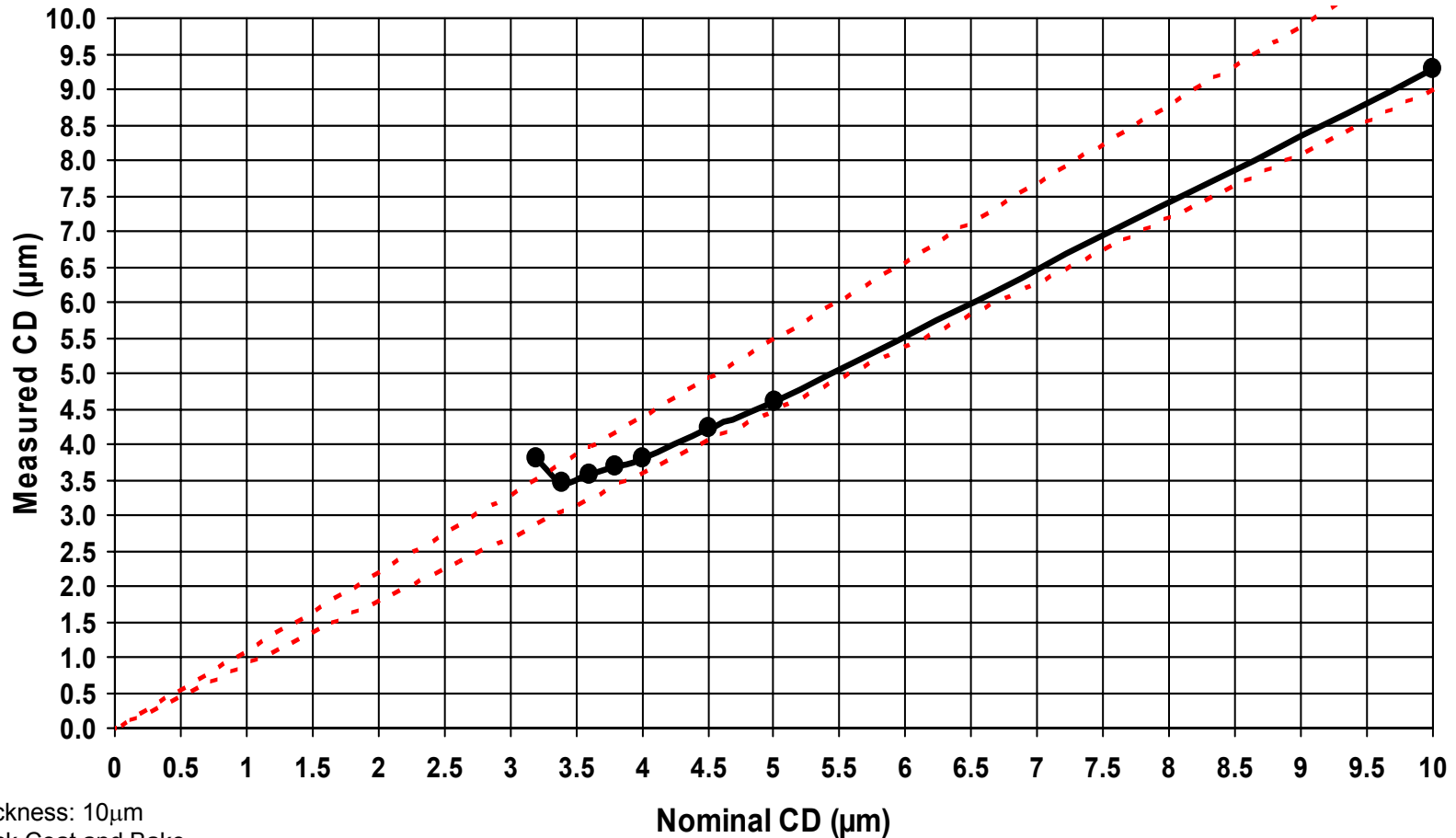
## FT = 10 μm, Focus = 1.0 μm, 5.0 μm L/S on Cu Wafers



Film Thickness: 10μm  
Opti Track Coat and Bake  
SB: 110°C/3 minutes  
ASML i-Line Stepper, F= +1.0μm  
Opti Track PEB/Develop  
PEB: 120°C/ 60 Seconds  
AZ 300 MIF/ 3x50sec Spray/Puddle @23°C

# AZ<sup>®</sup> 15nXT (450 CPS)

## L/S Linearity @ 300 mJ/cm<sup>2</sup>, F = +1.0 μm

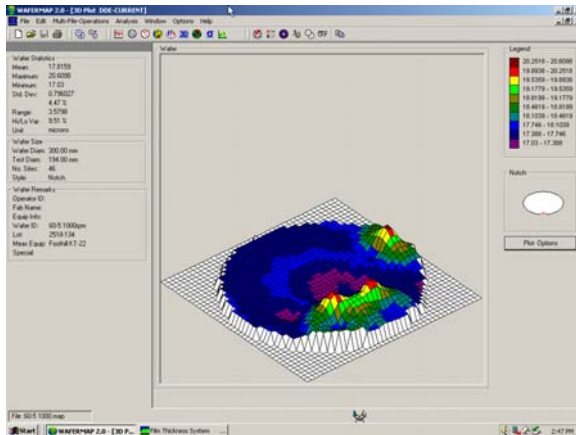


Film Thickness: 10μm  
Opti Track Coat and Bake  
SB: 110°C/3 minutes  
ASML i-Line Stepper, F= +1.0μm  
Opti Track PEB/Develop  
PEB: 120°C/ 60 Seconds  
AZ 300 MIF/ 3x50sec Spray/Puddle @23°C

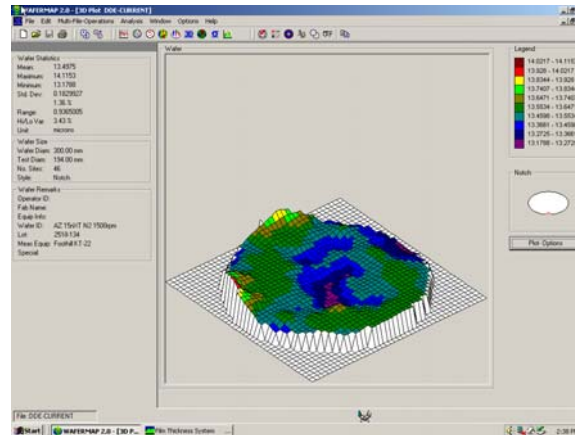
# AZ<sup>®</sup> 15nXT (450 CPS)

## Coating Uniformity Wafer Maps (3 mm Edge Exclusion)

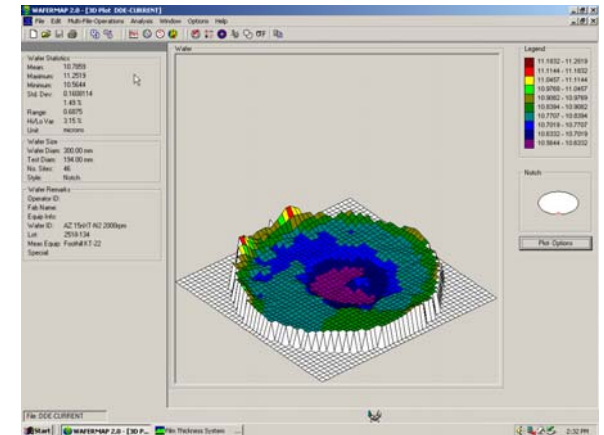
1000 rpm 17.8 $\mu$ m/4.49%RSD



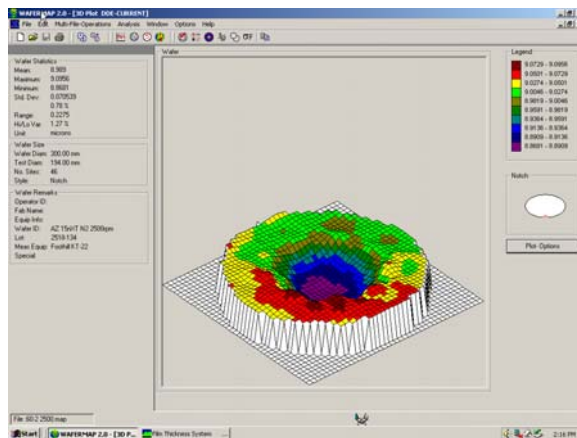
1500 rpm 13.5 $\mu$ m/1.36%RSD



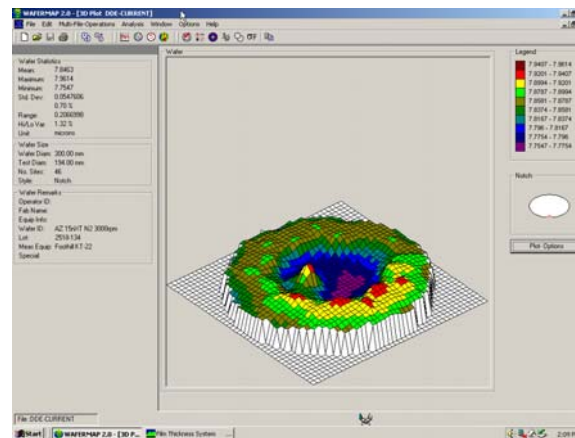
2000 rpm 10.8 $\mu$ m/1.49%RSD



2500 rpm 9.0 $\mu$ m/0.78%RSD

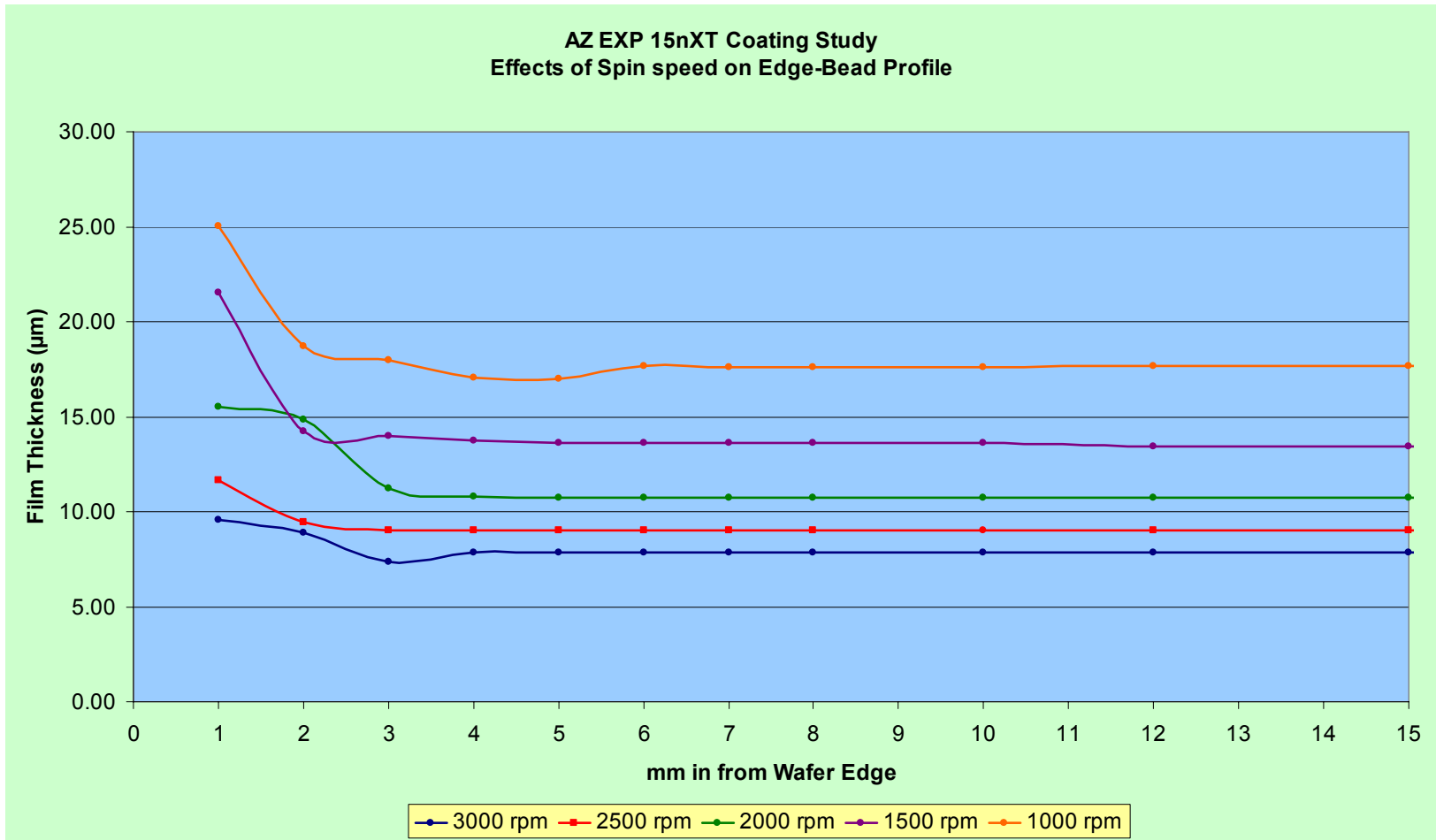


3000 rpm 7.8 $\mu$ m/0.70%RSD

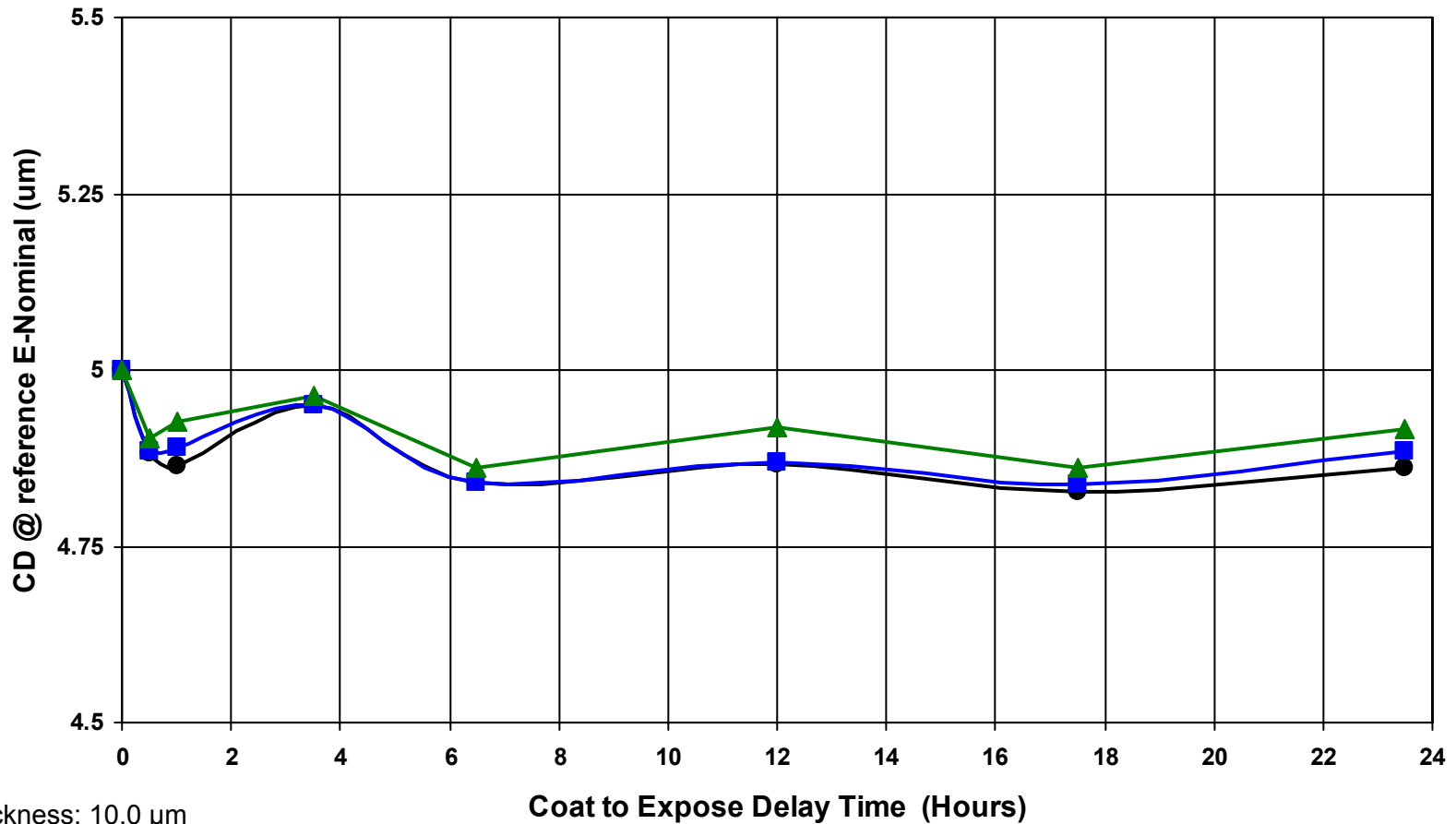


# AZ<sup>®</sup> 15nXT (450 CPS)

## Edge-Bead Coating Study (200 mm wafer)



# AZ<sup>®</sup> 15nXT (450 CPS), FT=10.0 $\mu\text{m}$ Coat to Exposure Delay on Copper; 5 $\mu\text{m}$ L/S



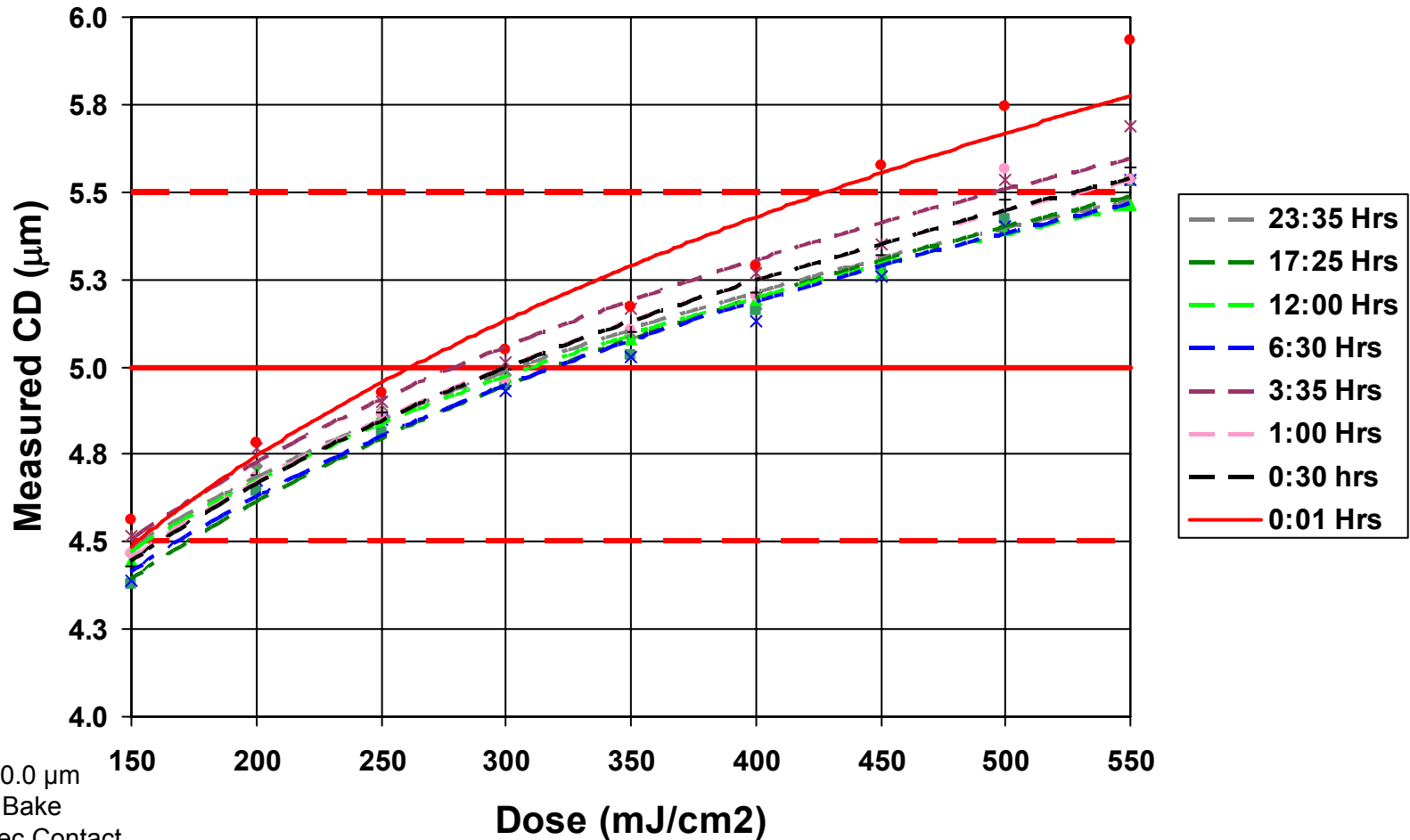
Film Thickness: 10.0  $\mu\text{m}$   
 Optitrac coat and Bake  
 SB: 110°C/ 180 sec Contact  
 ASML 0.48 NA 0.55  $\sigma$  i-Line  
 PEB: 120°C/ 60 sec Contact  
 AZ 300 MIF 3x50 sec spray puddles @ 23 °C

—●— F=0.5 —■— F=1.0 —▲— F=1.5



# AZ<sup>®</sup> 15nXT (450 CPS) , F = +1.0 μm, FT=10.0 μm

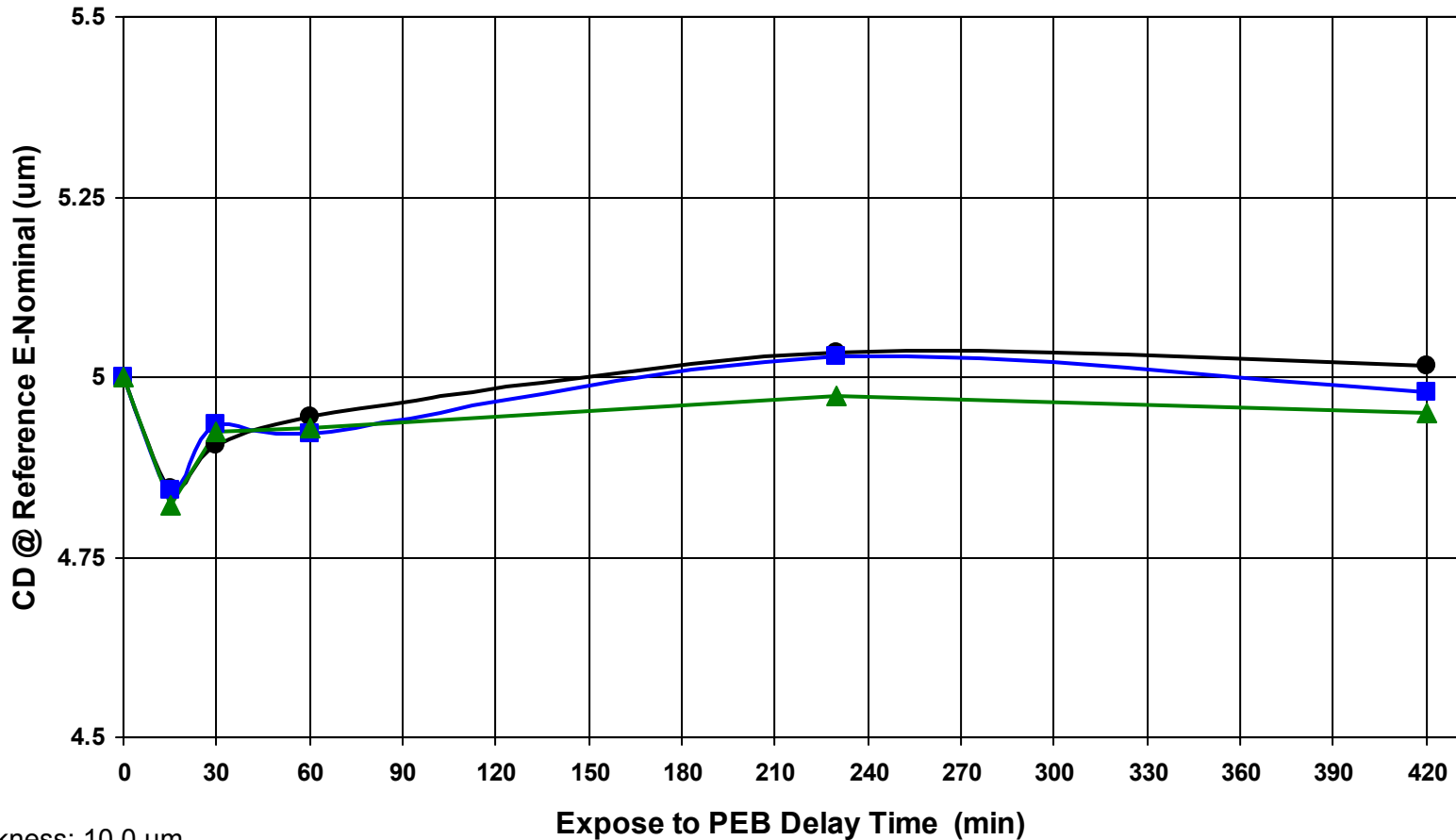
## Coat to Exposure Delay on Copper (hr:mm); 5 μm L/S



Film Thickness: 10.0 μm  
Optitrac coat and Bake  
SB: 110°C/ 180 sec Contact  
ASML 0.48 NA 0.55 σ i-Line  
PEB: 120°C/ 60 sec Contact  
AZ 300 MIF 3x50 sec spray puddles @ 23 °C

# AZ<sup>®</sup> 15nXT (450 CPS) , FT=10.0 μm

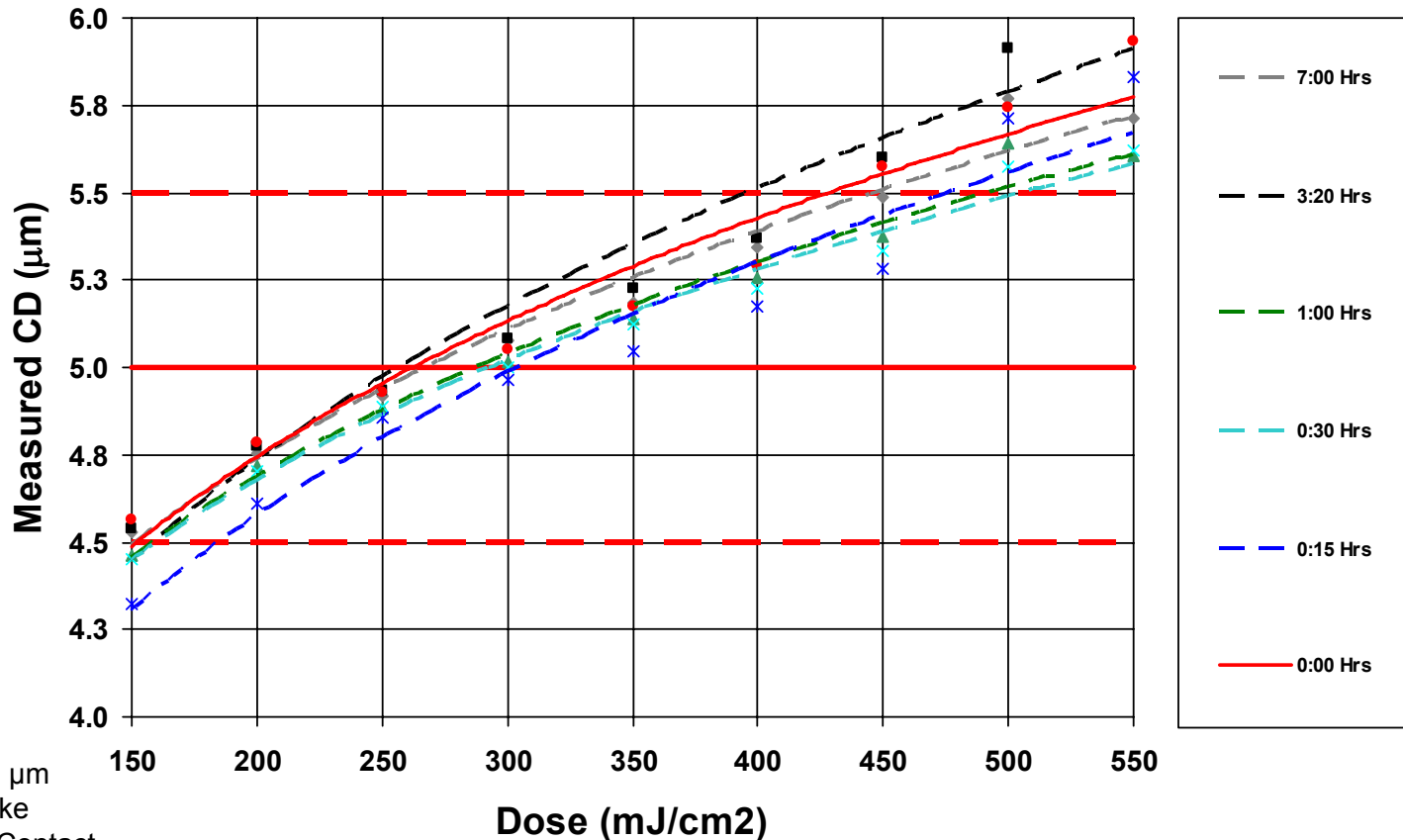
## Exposure to PEB Delay on Cu Wafers; 5 μm L/S



Film Thickness: 10.0 μm  
 Optitrac coat and Bake  
 SB: 110°C/ 180 sec Contact  
 ASML 0.48 NA 0.55 σ i-Line  
 PEB: 120°C/ 60 sec Contact  
 AZ 300 MIF 3x50 sec spray puddles @ 23 °C

—●— F=0.5 —■— F=1.0 —▲— F=1.5

# AZ<sup>®</sup> 15nXT (450 CPS), F = +1.0 μm, FT=10.0 μm Exposure to PEB Delay on Cu Wafers (Hr:mm); 5 μm L/S



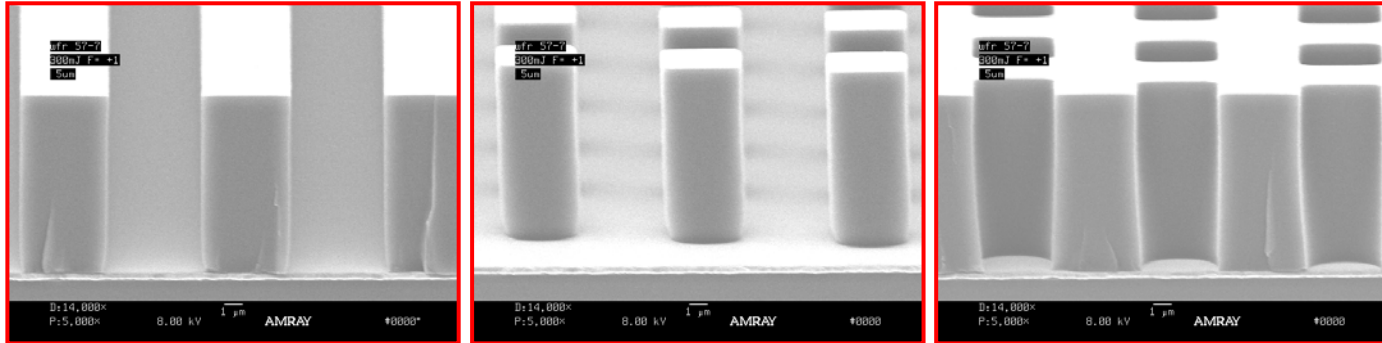
Film Thickness: 10.0 μm  
 Optitrac coat and Bake  
 SB: 110°C/ 180 sec Contact  
 ASML 0.48 NA 0.55 σ i-Line  
 PEB: 120°C/ 60 sec Contact  
 AZ 300 MIF 3x50 sec spray puddles @ 23 °C

# AZ<sup>®</sup> 15nXT (450 CPS)

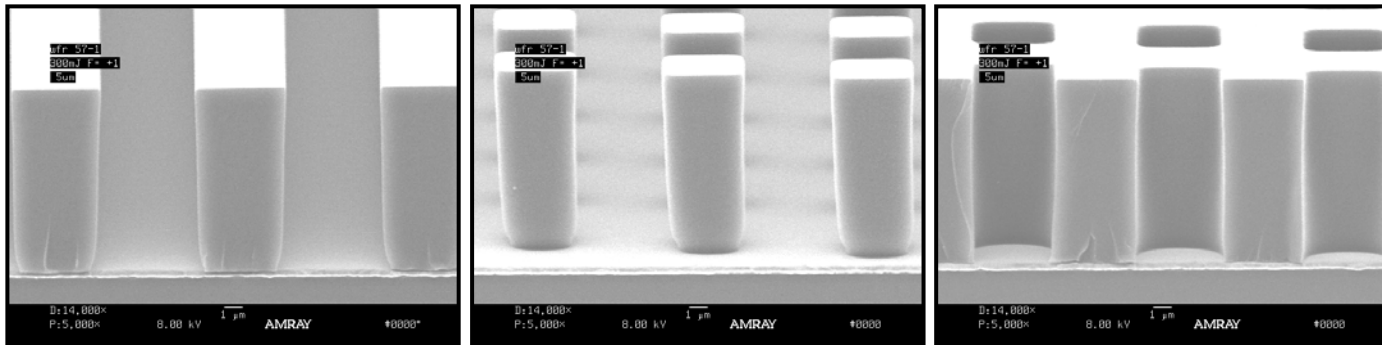
## Exposure and PEB Delays on Cu Wafers

300 mJ/cm<sup>2</sup>, FT=10.0 μm, 5μm Features @ F= +1.0

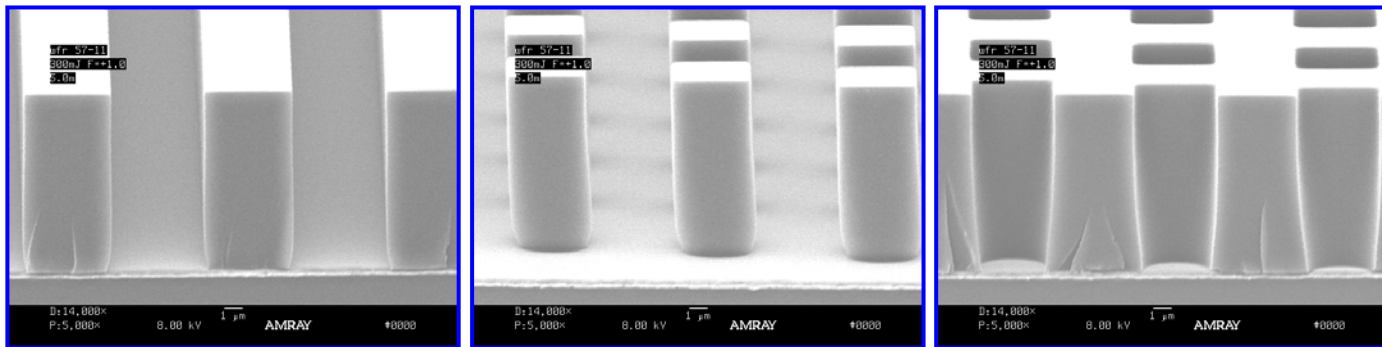
No  
Delays



Exposure  
+ 23 Hours



PEB/Develop  
+ 7 Hours



# AZ<sup>®</sup> 15nXT (450 CPS)

## Ni/Cu Plating Compatibility

Ni Plating solution: Enthone Microfab Ni-100

Process condition:

Electrical density: 3.2 ASD

Plating current: 0.103 A

Stirring rate: 120 rpm

Temp: 50°C

Plating time: 3 min 12 sec

Cu Plating solution: Enthone Microfab Cu 200

Process condition:

Electrical density: 3.2 ASD

Plating current: 0.103 A

Stirring rate: 120 rpm

Temp: 25°C (Room Temp)

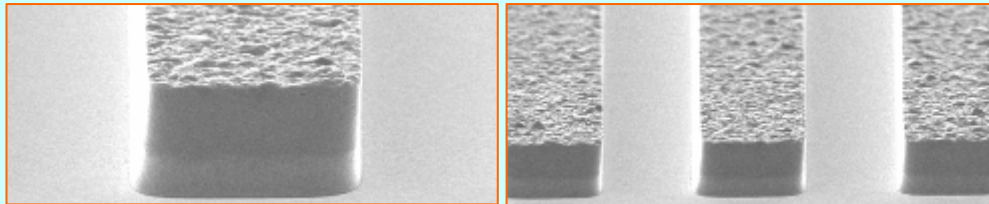
Plating time: 4 min 48 sec

Stripping: AZ<sup>®</sup> Kwik Strip at 70 °C for 3 min

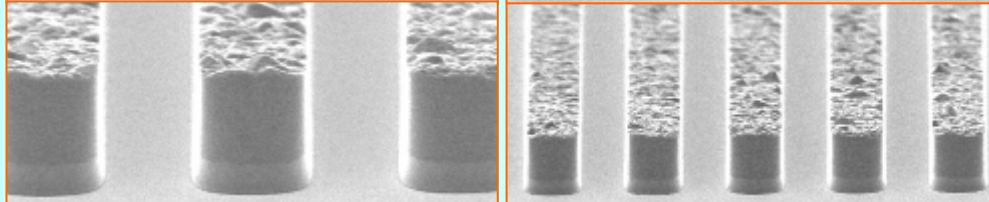
**AZ<sup>®</sup> 15nXT (450 CPS)**  
**Plated Ni/Cu Lines**

**AZ<sup>®</sup> 15nXT (450 CPS)**  
**F=1 $\mu$ m; 400 mJ/cm<sup>2</sup>**

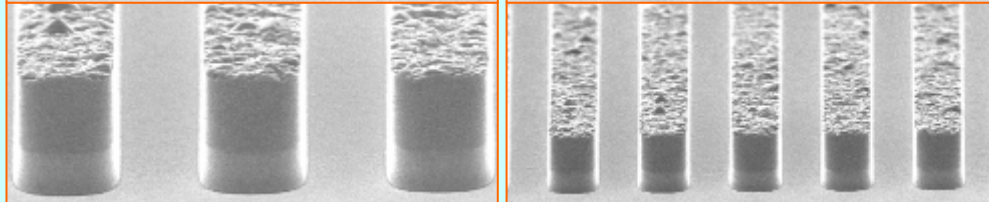
10  $\mu$ m



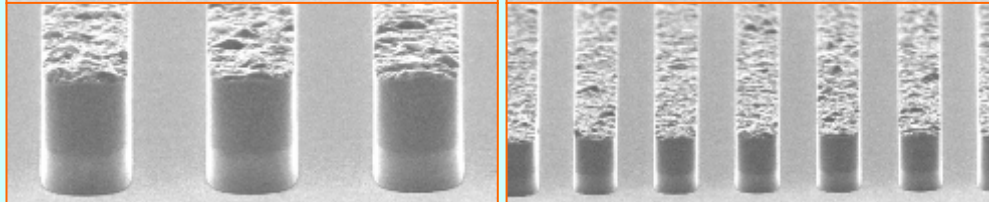
5  $\mu$ m



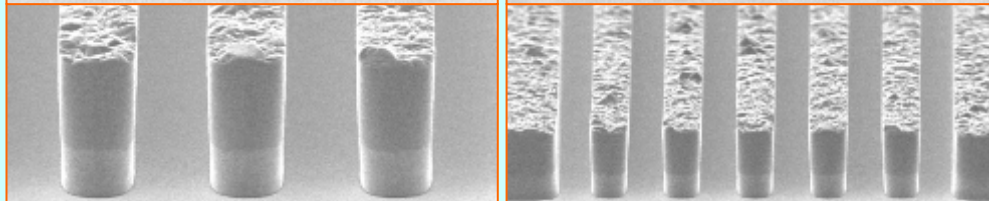
4.5  $\mu$ m



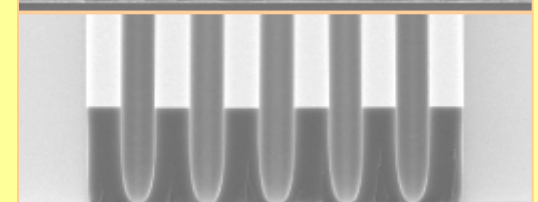
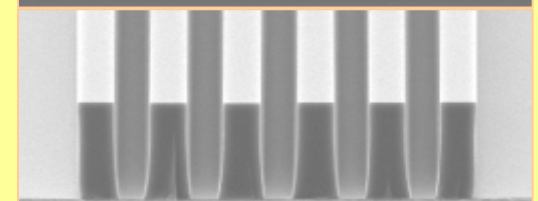
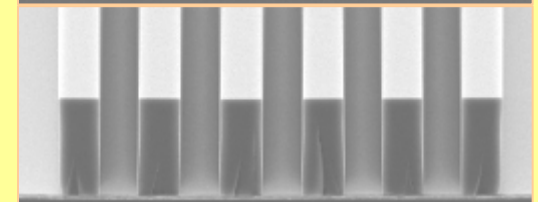
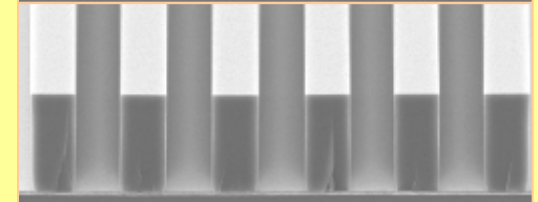
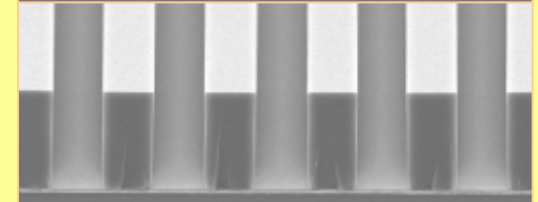
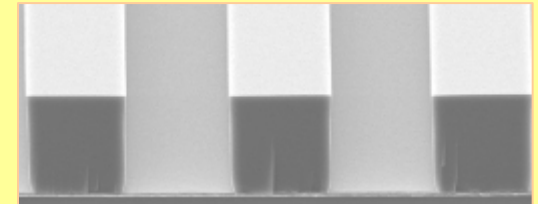
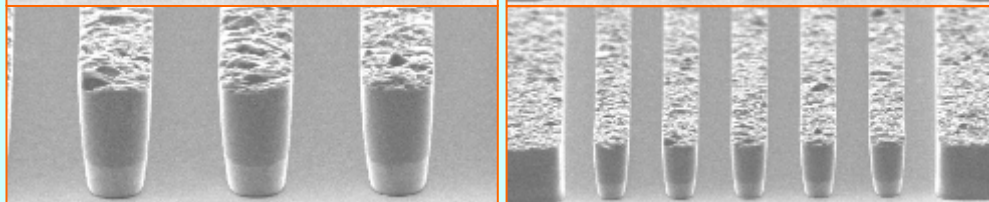
4  $\mu$ m



3.6  $\mu$ m



3.4  $\mu$ m



# AZ<sup>®</sup> 15nXT (450 CPS) Summary

- ▲ Compatible on Cu type substrates and other metals.
- ▲ Very good lithographic throughput; very competitive photospeed and develop time.
- ▲ Excellent adhesion, no underplating.
- ▲ Vertical sidewall profiles.
- ▲ Wide compatibility to plating solutions, including Cu, Ni, and Au.
- ▲ Easily strips after plating; stripped completely in AZ Kwik Strip at 70°C for 3 min.
- ▲ Very good stability and shelf life
- ▲ Thinner version available for lower FT range; 15nXT (115 CPS).